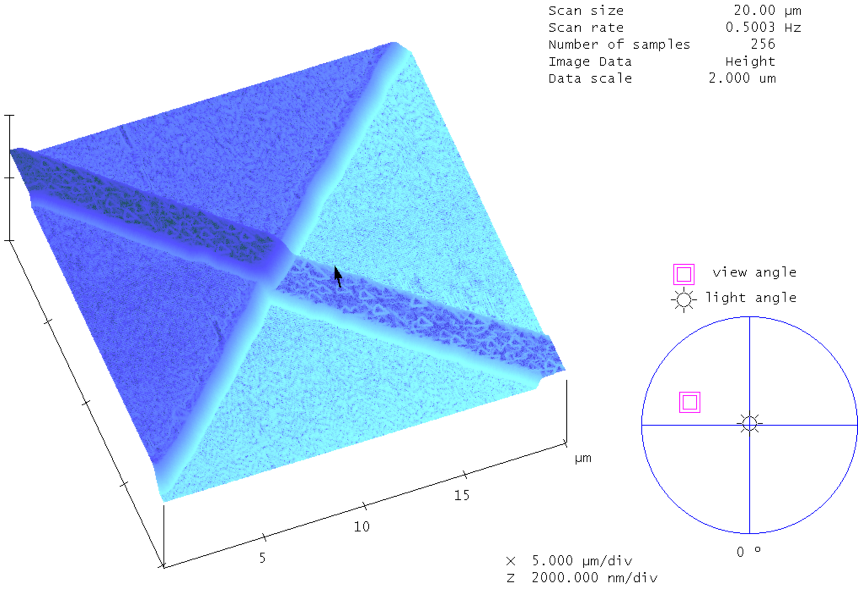
Master
Nanotech

N2: Contact mode AFM

This practical is focused on the atomic force microscope (AFM) in contact mode. It is divided into two parts: the first concerning the AFM as a topography measurement tool and the second presenting an application of the AFM for nano-fabrication.

The objectives of this practical are: to understand how an AFM works in contact mode, to learn how to use it in order to obtain correct images, to analyze the images obtained and to use it as a nano-fabrication tool.

The figure below shows a typical image of the gate of one of the transistors that are fabricated in the clean-room, during the technology lab sessions.



```
Scan size              20.00 µm
Scan rate             0.5003 Hz
Number of samples        256
Image Data            Height
Data scale           2.000 um
```